

BOX AF
REPLY UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2814

PATENT
2342-0107P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: Mitsuhiko HIRANO Conf.: 3165
Appl. No.: 08/813,200 Group: 2814
Filed: March 7, 1997 Examiner: S. RAO
For: SUBSTRATE PROCESSING APPARATUS WITH LOCAL
EXHAUST FOR REMOVING CONTAMINANTS

REPLY UNDER 37 C.F.R. § 1.116

Assistant Commissioner of Patents
and Trademarks
Washington, D.C. 20231

February 13, 2002

Sir:

This is a reply to the Office Action mailed August 13, 2001.

AMENDMENT

IN THE CLAIMS

Please amend the claims as follows:

10. (Five Times Amended) A substrate processing apparatus comprising:
- a substrate processing chamber for processing a substrate;
 - a load lock chamber;
 - a gas supply for supplying gas into said load lock chamber;